

Contents

About the Special Issue Editors	vii
Mahmoud Rasras, Ibrahim (Abe) M. Elfadel and Ha Duong Ngo Editorial for the Special Issue on MEMS Accelerometers Reprinted from: <i>Micromachines</i> 2019, 10, 290, doi:10.3390/mi10050290	1
Xiaofeng Zhao, Ying Wang and Dianzhong Wen Fabrication and Characteristics of a SOI Three-Axis Acceleration Sensor Based on MEMS Technology Reprinted from: <i>Micromachines</i> 2019, 10, 238, doi:10.3390/mi10040238	4
Zhaohua Yang, Dan Li and Yuzhe Sun Analysis of Kerr Noise in Angular-Rate Sensing Based on Mode Splitting in a Whispering-Gallery-Mode Microresonator Reprinted from: <i>Micromachines</i> 2019, 10, 150, doi:10.3390/mi10020150	17
Cheng Yuan, Jizhou Lai, Pin Lyu, Peng Shi, Wei Zhao and Kai Huang A Novel Fault-Tolerant Navigation and Positioning Method with Stereo-Camera/Micro Electro Mechanical Systems Inertial Measurement Unit (MEMS-IMU) in Hostile Environment Reprinted from: <i>Micromachines</i> 2018, 9, 626, doi:10.3390/mi9120626	25
Zakriya Mohammed, Ibrahim (Abe) M. Elfadel and Mahmoud Rasras Monolithic Multi Degree of Freedom (MDoF) Capacitive MEMS Accelerometers Reprinted from: <i>Micromachines</i> 2018, 9, 602, doi:10.3390/mi9110602	44
Fufu Wang, Lu Zhang, Long Li, Zhihong Qiao and Qian Cao Design and Analysis of the Elastic-Beam Delaying Mechanism in a Micro-Electro-Mechanical Systems Device Reprinted from: <i>Micromachines</i> 2018, 9, 567, doi:10.3390/mi9110567	64
Haitao Liu, Kai Wei, Zhengzhou Li, Wengang Huang, Yi Xu and Wei Cui A Novel, Hybrid-Integrated, High-Precision, Vacuum Microelectronic Accelerometer with Nano-Field Emission Tips Reprinted from: <i>Micromachines</i> 2018, 9, 481, doi:10.3390/mi9100481	77
Wei Yang, Chundi Xiu, Jiarui Ye, Zhixing Lin, Haisong Wei, Dayu Yan and Dongkai Yang LSS-RM: Using Multi-Mounted Devices to Construct a Lightweight Site-Survey Radio Map for WiFi Positioning Reprinted from: <i>Micromachines</i> 2018, 9, 458, doi:10.3390/mi9090458	89
Wen-Yen Lin, Vijay Kumar Verma, Ming-Yih Lee and Chao-Sung Lai Activity Monitoring with a Wrist-Worn, Accelerometer-Based Device Reprinted from: <i>Micromachines</i> 2018, 9, 450, doi:10.3390/mi9090450	113
Dongliang Chen, Xiaowei Liu, Liang Yin, Yinhang Wang, Zhaohu Shi and Guorui Zhang A $\Sigma \Delta$ Closed-Loop Interface for a MEMS Accelerometer with Digital Built-In Self-Test Function Reprinted from: <i>Micromachines</i> 2018, 9, 444, doi:10.3390/mi9090444	125
Sen Qiu, Long Liu, Hongyu Zhao, Zhelong Wang and Yongmei Jiang MEMS Inertial Sensors Based Gait Analysis for Rehabilitation Assessment via Multi-Sensor Fusion Reprinted from: <i>Micromachines</i> 2018, 9, 442, doi:10.3390/mi9090442	148

Jae-Neung Lee, Yeong-Hyeon Byeon and Keun-Chang Kwak
 Design of Ensemble Stacked Auto-Encoder for Classification of Horse Gaits with MEMS Inertial Sensor Technology
 Reprinted from: *Micromachines* 2018, 9, 411, doi:10.3390/mi9080411 165

Jae Keon Kim, Maeum Han, Shin-Won Kang, Seong Ho Kong and Daewoong Jung
 Multi-axis Response of a Thermal Convection-based Accelerometer
 Reprinted from: *Micromachines* 2018, 9, 329, doi:10.3390/mi9070329 182

Bian Tian, Huafeng Li, Hua Yang, Yulong Zhao, Pei Chen and Dalei Song
 Design and Performance Test of an Ocean Turbulent Kinetic Energy Dissipation Rate Measurement Probe
 Reprinted from: *Micromachines* 2018, 9, 311, doi:10.3390/mi9060311 195

Xiaodong Hu, Piotr Mackowiak, Manuel Bäuscher, Oswin Ehrmann, Klaus-Dieter Lang, Martin Schneider-Ramelow, Stefan Linke and Ha-Duong Ngo
 Design and Application of a High-G Piezoresistive Acceleration Sensor for High-Impact Application
 Reprinted from: *Micromachines* 2018, 9, 266, doi:10.3390/mi9060266 211

Xianshan Dong, Shaohua Yang, Junhua Zhu, Yunfei En and Qinwen Huang
 Method of Measuring the Mismatch of Parasitic Capacitance in MEMS Accelerometer Based on Regulating Electrostatic Stiffness
 Reprinted from: *Micromachines* 2018, 9, 128, doi:10.3390/mi9030128 219

Huan Liu, Runiu Fang, Min Miao, Yichuan Zhang, Yingzhan Yan, Xiaoping Tang, Huixiang Lu and Yufeng Jin
 Design, Fabrication, and Performance Characterization of LTCC-Based Capacitive Accelerometers
 Reprinted from: *Micromachines* 2018, 9, 120, doi:10.3390/mi9030120 227